

**Supplementary Information:** AA16: Emerging: Others (Protective Coatings, Hardness, MEMs ...)

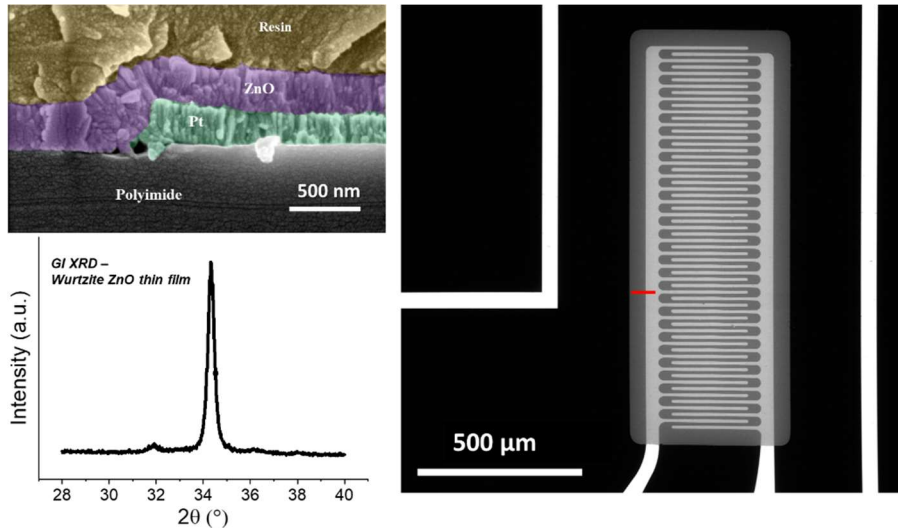


Figure 1 - Controlled of the wurtzite ZnO (002) orientation by thermal ALD on polymer and metal surfaces to obtain a strain sensor based on a diode junction. The SEM cross-section (left) detailed the red profile on the SEM top view micrograph (right) of the sensor microstructured in our cleanroom facilities (Courtesy: J. Polese).

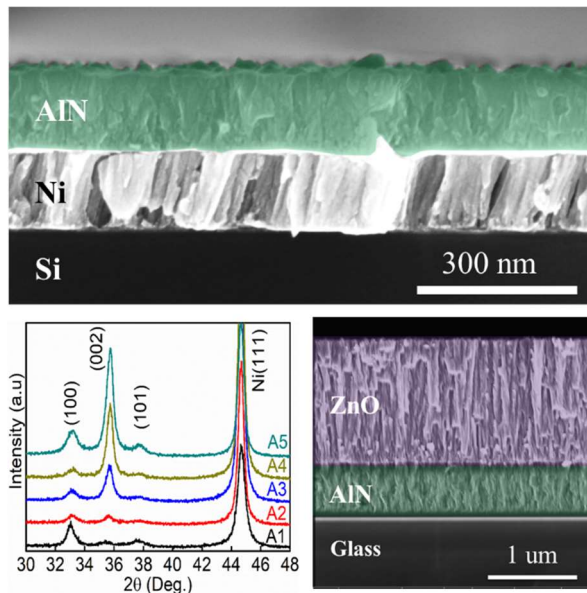


Figure 2 - A high quality piezoelectric AlN films deposited by PEALD energy harvesting application. The stacking of several functional layers has been made with nickel (111) and ZnO (002). Controlled conditions of ALD processes (A1 to A5) allows to modulate the crystalline structure (XRD) of AlN. (Courtesy: J. Polese).

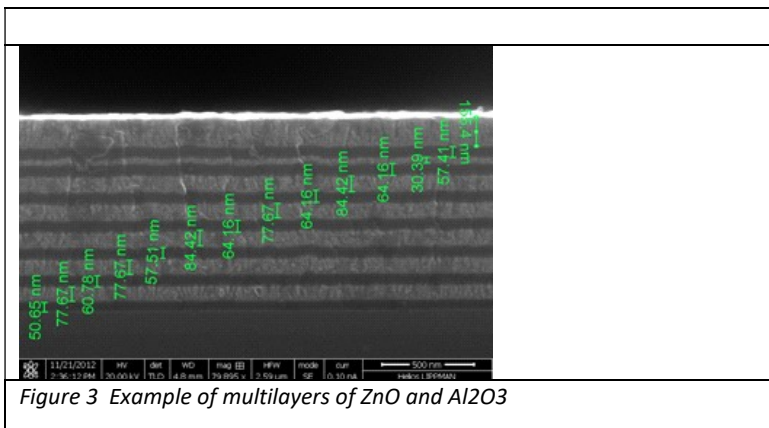


Figure 3 Example of multilayers of ZnO and Al<sub>2</sub>O<sub>3</sub>

